

PATENT
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Maximilian A. Biberger et al.

Serial No.: 09/912,844

Filed: July 24, 2001

For: **HIGH PRESSURE PROCESSING
CHAMBER FOR
SEMICONDUCTOR SUBSTRATE**

Group Art Unit: 1763

Examiner: Ram N. Kackar

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Mail Stop Non-Fee Amendment
Commissioner for Patents
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Sir:

Please amend the above-titled application as follows:

CERTIFICATE OF FACSIMILE TRANSMISSION	
I hereby certify that this paper (along with any referred to as being attached or enclosed) is being facsimile transmitted to the Patent and Trademark Office at:	
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